



Dispositivos micromecânicos para caracterização de materiais

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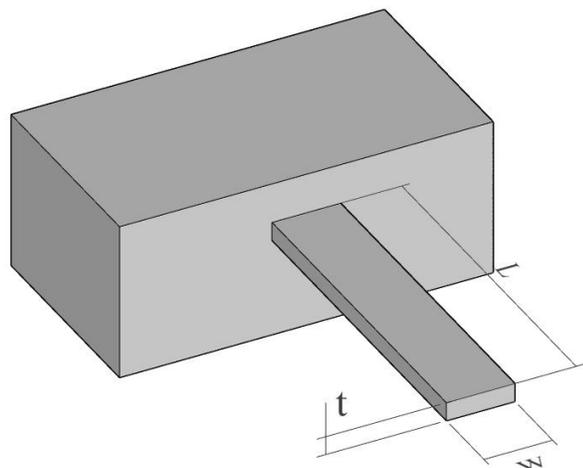


Conteúdo

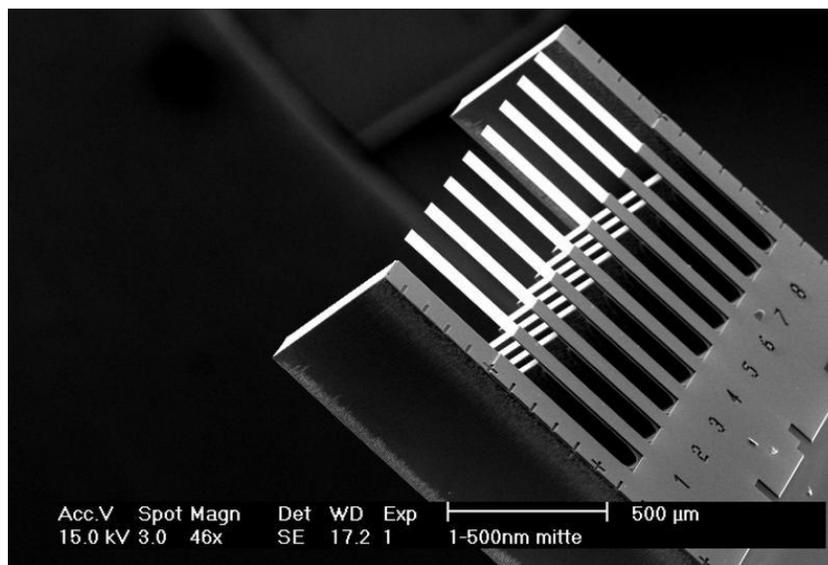
- Introdução (8 slides)
- Sistemas de medidas (7 slides)
- Caracterização térmica de materiais (5 slides)
- Fabricação de dispositivos poliméricos (1 slide)
- Caracterizações (2 slides)
- Estado da arte (4 slides)

Introdução

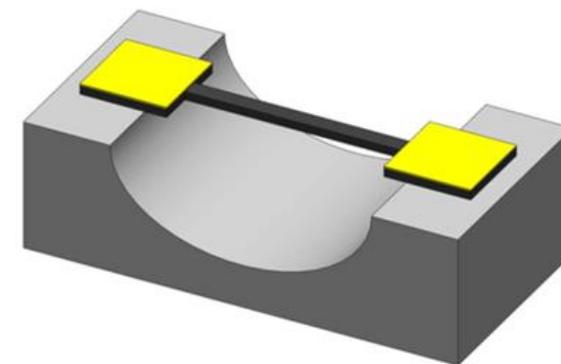
O Microcantilever é um dos dispositivos MEMS mais simples



Tamanhos usuais:
 $L = 100 - 500 \mu\text{m}$
 $w = 20 - 100 \mu\text{m}$
 $t = 0,5 \mu\text{m} - 10 \mu\text{m}$



Fonte :
<https://www.sciencedaily.com/releases/2013/02/130214075439.htm>



Fonte : <https://www.nature.com/articles/s41378-019-009>

1986 – Invenção do AFM na IBM

VOLUME 56, NUMBER 9

PHYSICAL REVIEW LETTERS

3 MARCH 1986

Atomic Force Microscope

G. Binnig^(a) and C. F. Quate^(b)

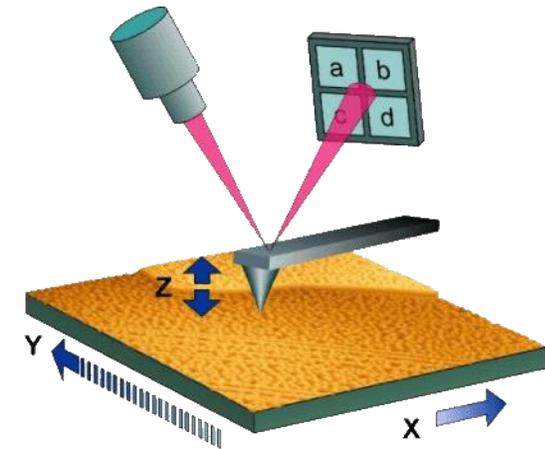
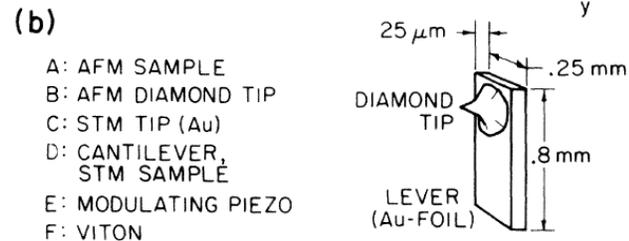
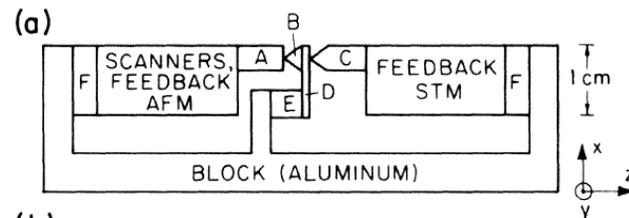
Edward L. Ginzton Laboratory, Stanford University, Stanford, California 94305

and

Ch. Gerber^(c)

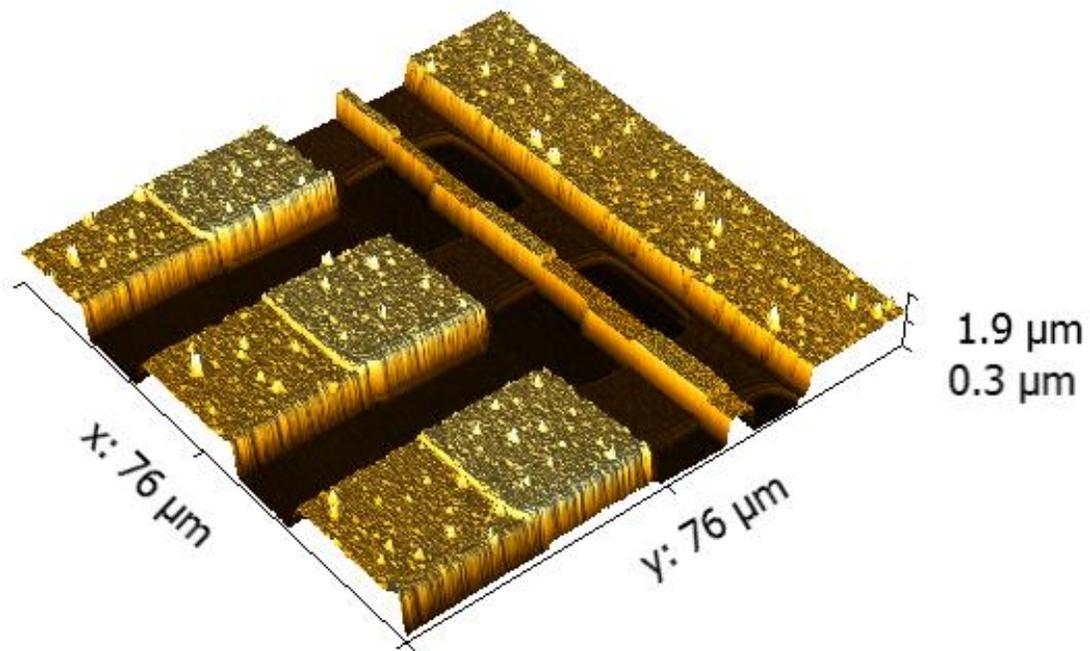
IBM San Jose Research Laboratory, San Jose, California 95193

(Received 5 December 1985)



A ampla utilização do AFM popularizou os cantileveres micrométricos.

Imagem AFM de uma cascata de transistores MOS (USP -2016)





Introdução

- 1994 – Primeira utilização de microcantilever do AFM como sensor

Thermal and ambient-induced deflections of scanning force microscope cantilevers

T. Thundat, R. J. Warmack, G. Y. Chen, and D. P. Allison
Oak Ridge National Laboratory, Oak Ridge, Tennessee 37831-6123

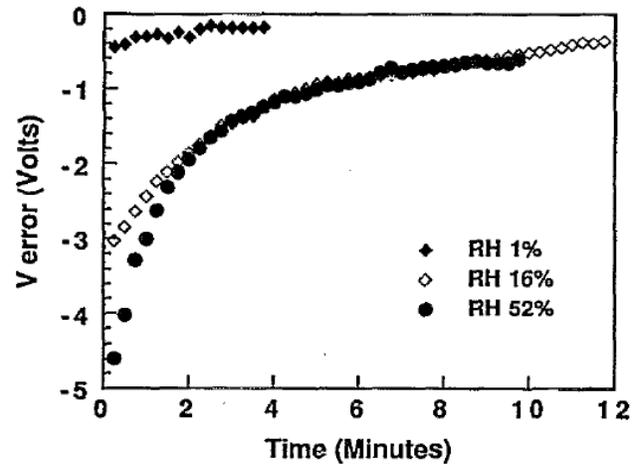


FIG. 1. Error voltage as a function of time for a microfabricated silicon cantilever with 40 nm gold overlayer for three different relative humidities. Initial values of the error voltage are arbitrary. Error bars are shown.

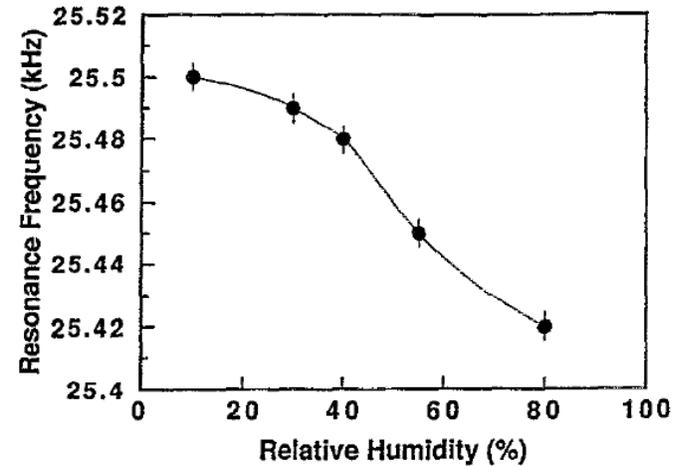


FIG. 3. Typical variation in resonance frequency as a function of relative humidity for an uncoated silicon cantilever ($K=0.03$ N/m).

- Mudanças de temperatura, umidade etc. causavam problemas nas imagens (*drift*)

Introdução

- 2000 Primeira utilização de microcantilever para reconhecimento molecular de pares de DNA

Translating Biomolecular Recognition into Nanomechanics

J. Fritz,^{1,2} M. K. Baller,^{1,2} H. P. Lang,^{1,2} H. Rothuizen,¹
 P. Vettiger,¹ E. Meyer,² H.-J. Güntherodt,² Ch. Gerber,^{1*}
 J. K. Gimzewski¹

We report the specific transduction, via surface stress changes, of DNA hy-

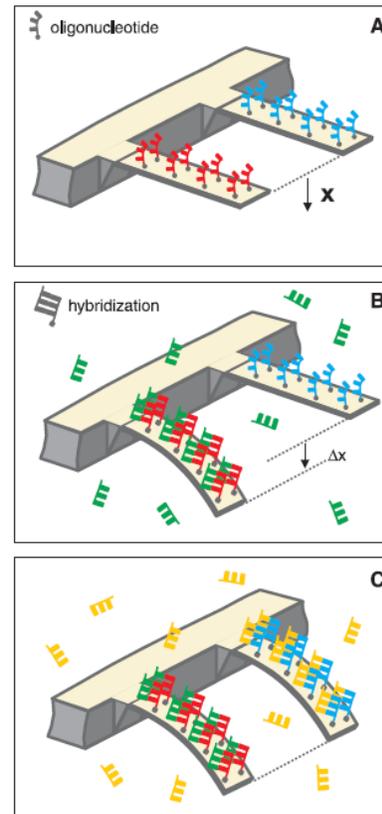
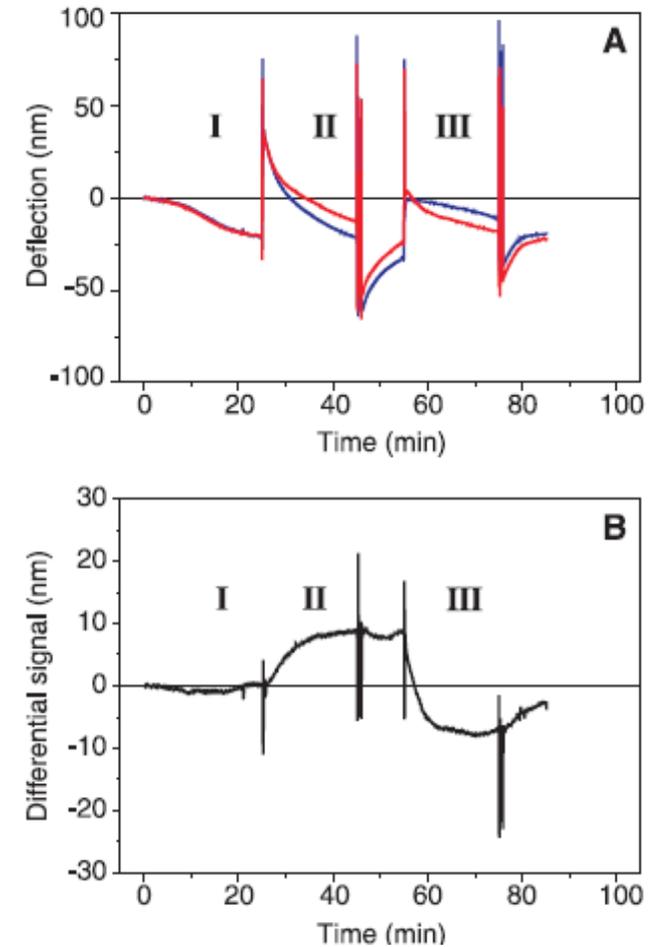
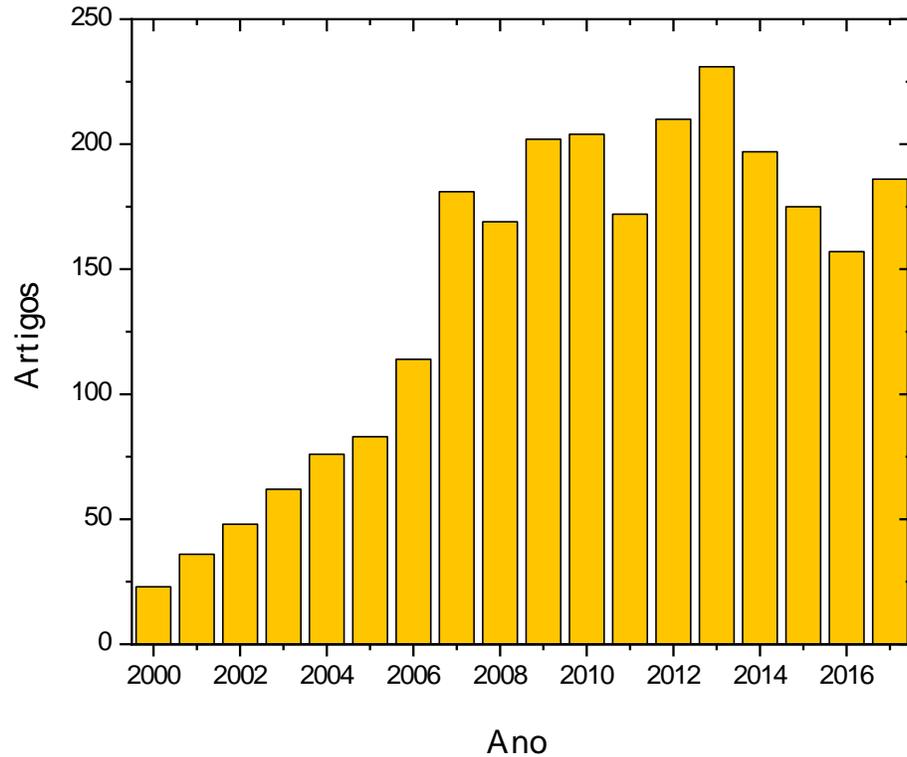


Fig. 2. Scheme illustrating the hybridization



Introdução



1 - Simples fabricação;

2 – Sensível;

3 - Versátil (múltiplas aplicações);

Artigos contendo “microcantilever sensor”
 Total de 2526 artigos nos últimos 17 anos

Introdução

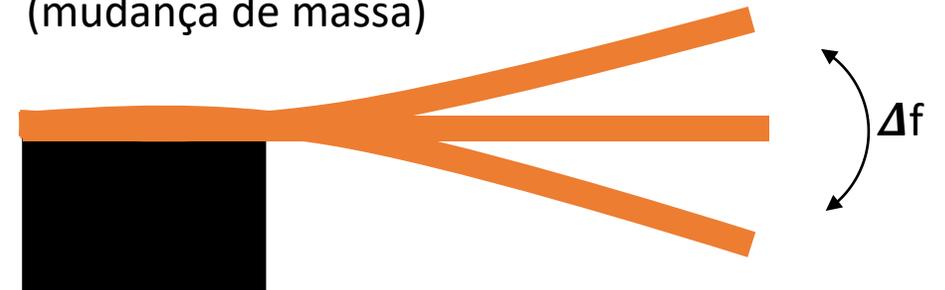
Princípio de funcionamento

Deflexão estática
(stress superficial)



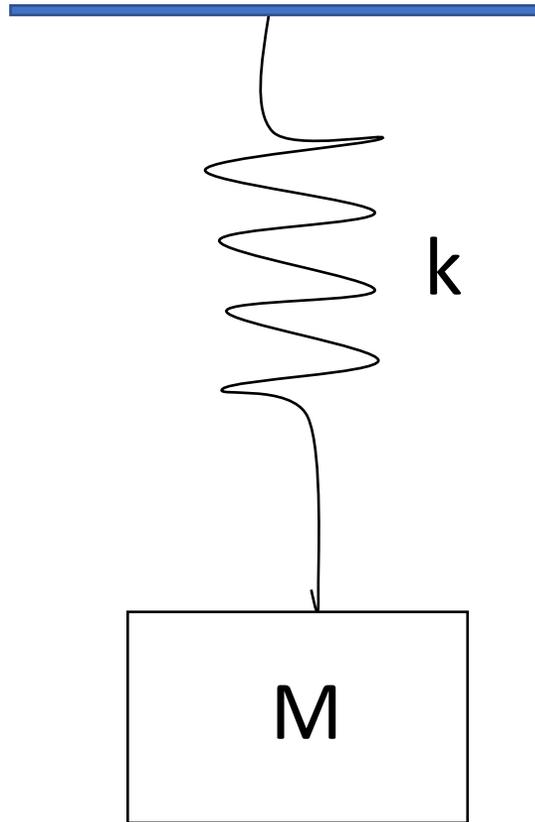
- Biosensores (reconhecimento biológico)
- Sensores de temperatura
- Nariz eletrônico
- Caracterização de materiais

Frequência de ressonância
(mudança de massa)



- Espectroscopia de massa
- Sensores de viscosidade
- Microfone
- Caracterização de materiais

Introdução Modelo



$$f = -k x$$

$$f = m \frac{d^2 x}{dt^2}$$

$$-k x = m \frac{d^2 x}{dt^2}$$

$$x(t) = \text{sen}(wt)$$

$$\dot{x}(t) = -w \cos(wt)$$

$$\ddot{x}(t) = -w^2 \text{sen}(wt)$$

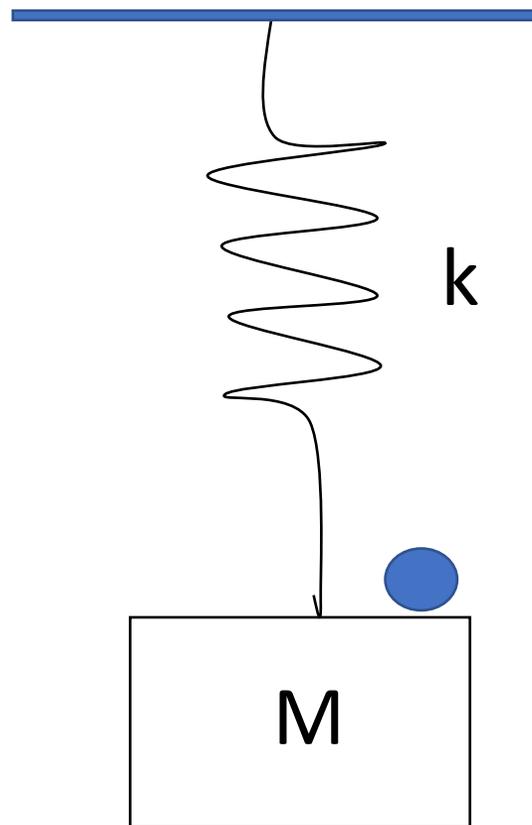
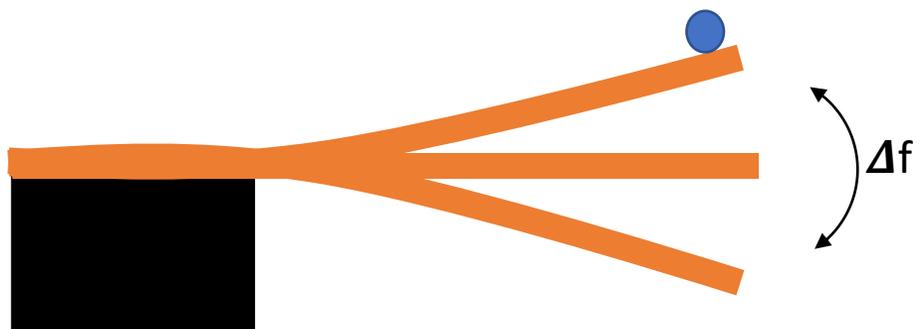
$$-k \text{sen}(wt) = -mw^2 \text{sen}(wt)$$

$$w = \sqrt{\frac{k}{m}} \quad w = \sqrt{\frac{k_{eff}}{m_{eff}}}$$



Introdução

Modelo



$$w = \sqrt{\frac{k_{eff}}{m_{eff}}}$$

$$S = \frac{dw}{dm} = \frac{w}{2m}$$

$$w = \frac{\alpha_n^2}{L^2} \sqrt{\frac{EI}{\rho A}}$$

$$\alpha_1 = 1,875, \alpha_2 = 4,6941, \alpha_3 = 7,854$$



Sistemas de medidas

Sistema de
medida de
deslocamento

Elétricos

- Piezoelétrico
- Piezo-resistivo
- Capacitivo

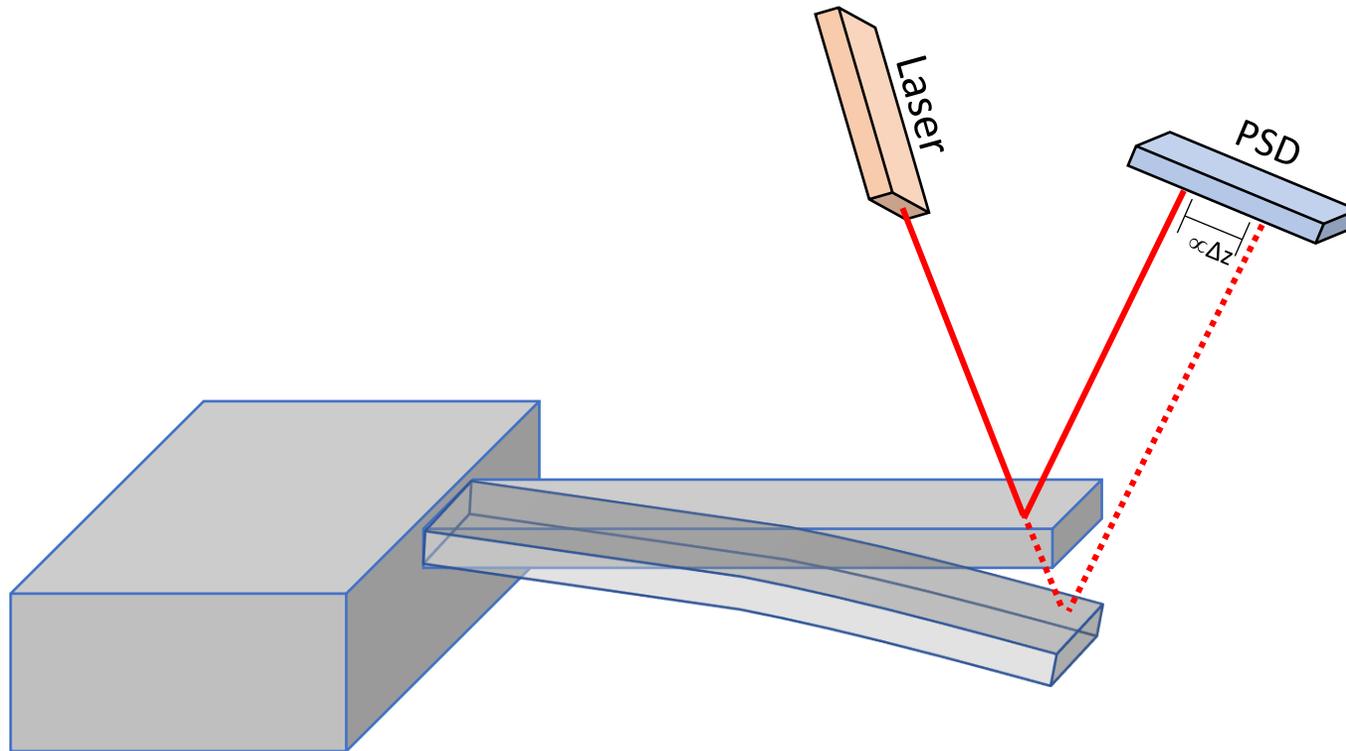
- Compactos e simples
- Ruidoso
- Menor resolução

Ópticos

- Triangulamento
- Velocimetria doppler/ Interferometria

- Menor ruído e Maior resolução
- Maiores e Mais complexos

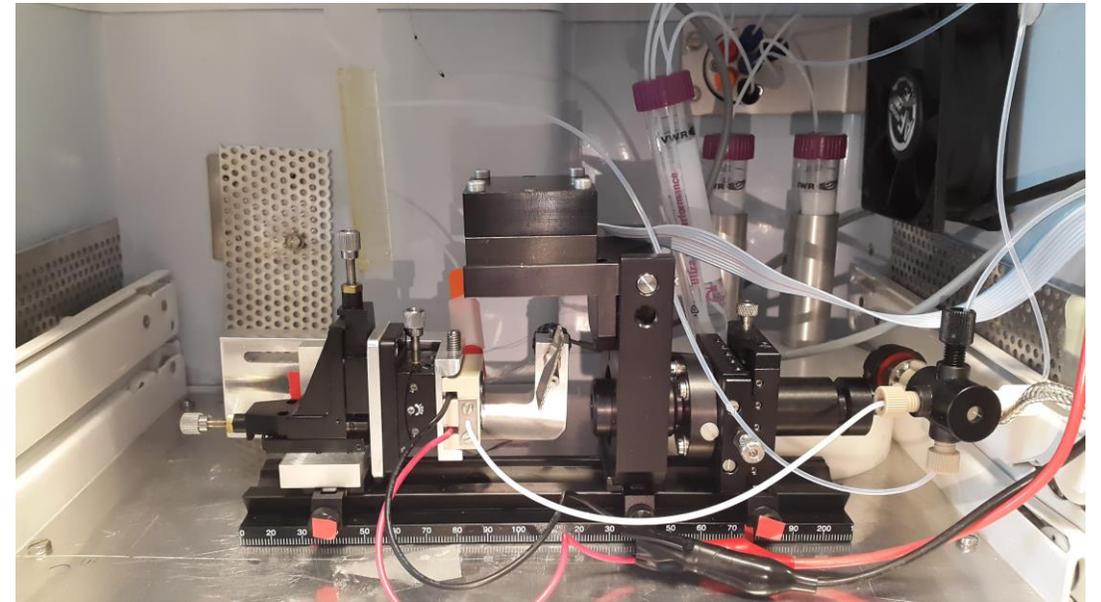
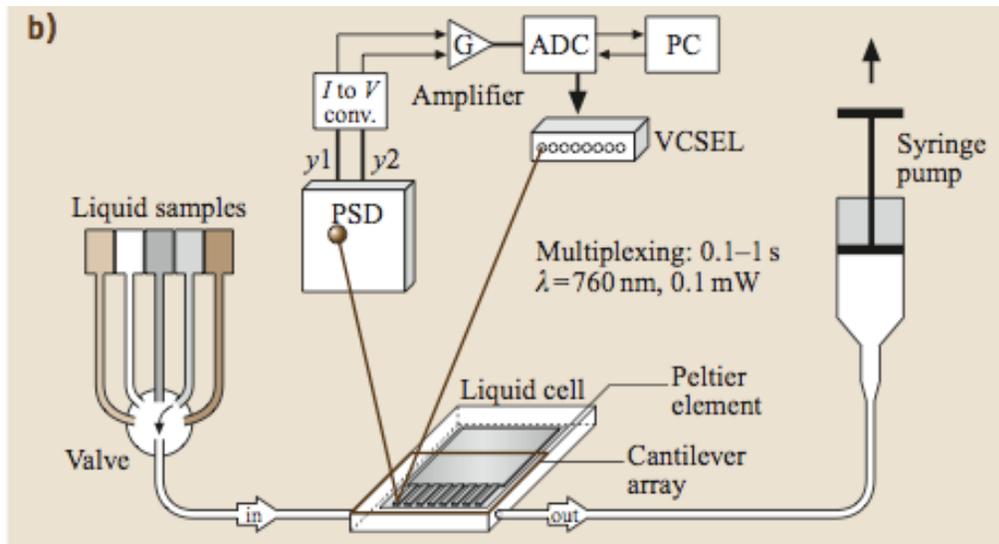
Sistema de medidas óptico por triangulamento



Sistema por triangulamento

- Utilizado em microscópios AFM
- Simples
- Não possibilita a leitura diferencial

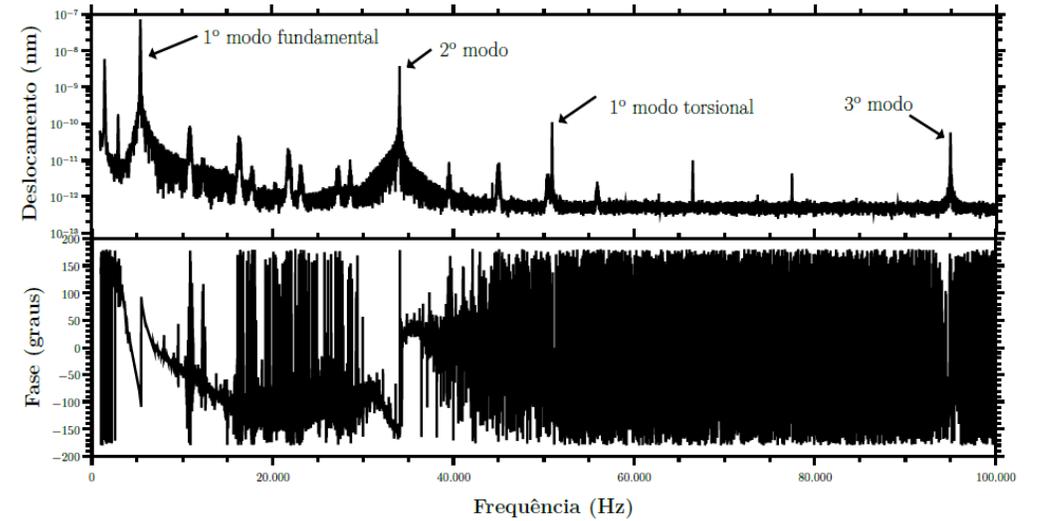
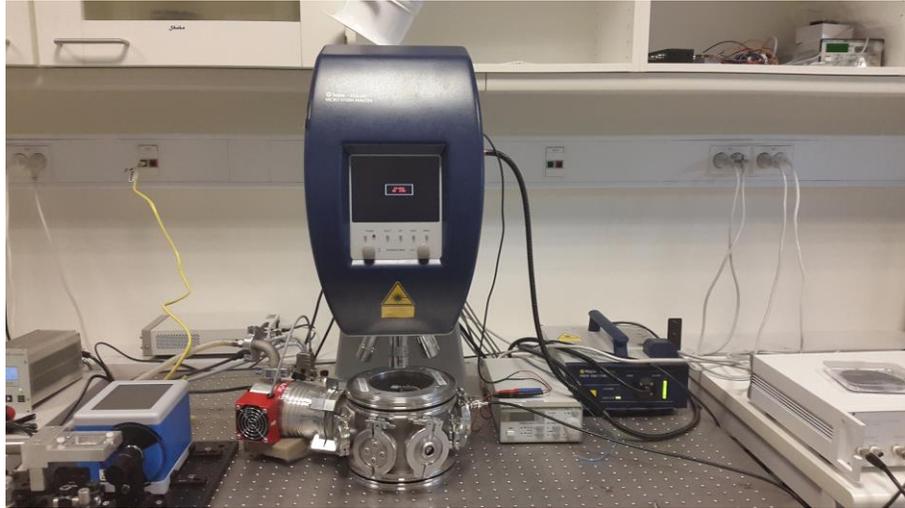
Sistema por triangulação “sl-nose”



Instrumentação

Vibrômetro Laser Doppler –

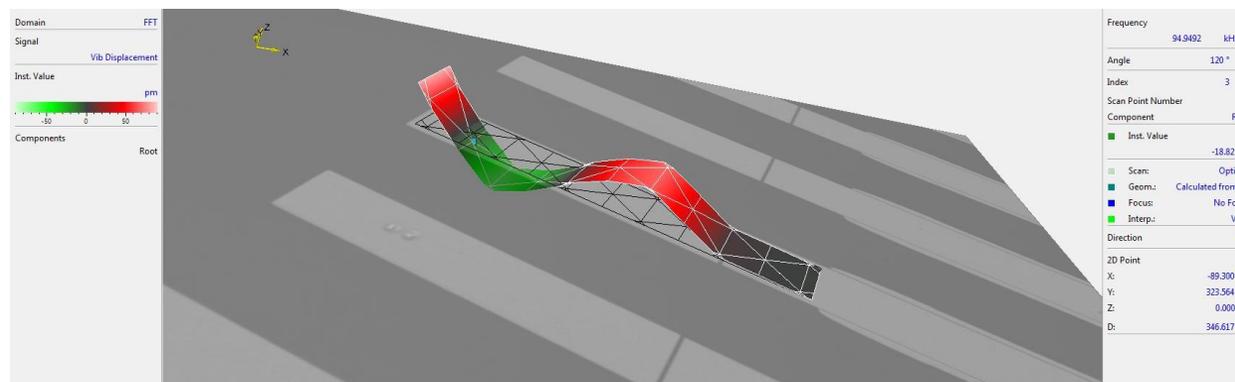
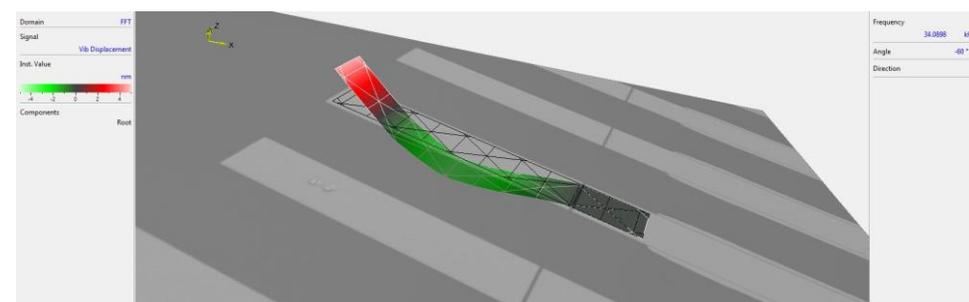
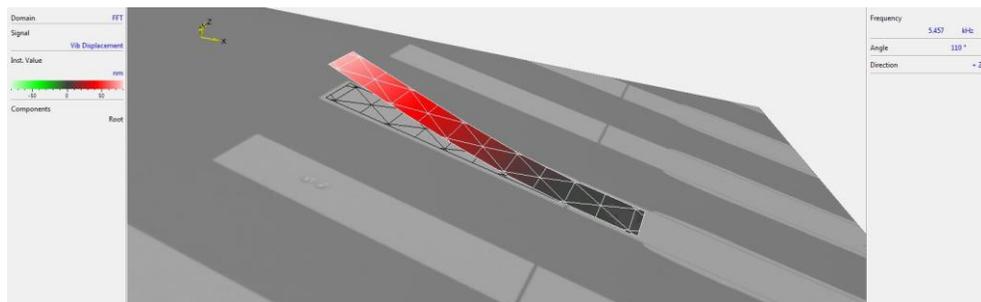
- Permite leitura de frequências de ressonância e modos de vibração.





Instrumentação

Vibrômetro Laser Doppler

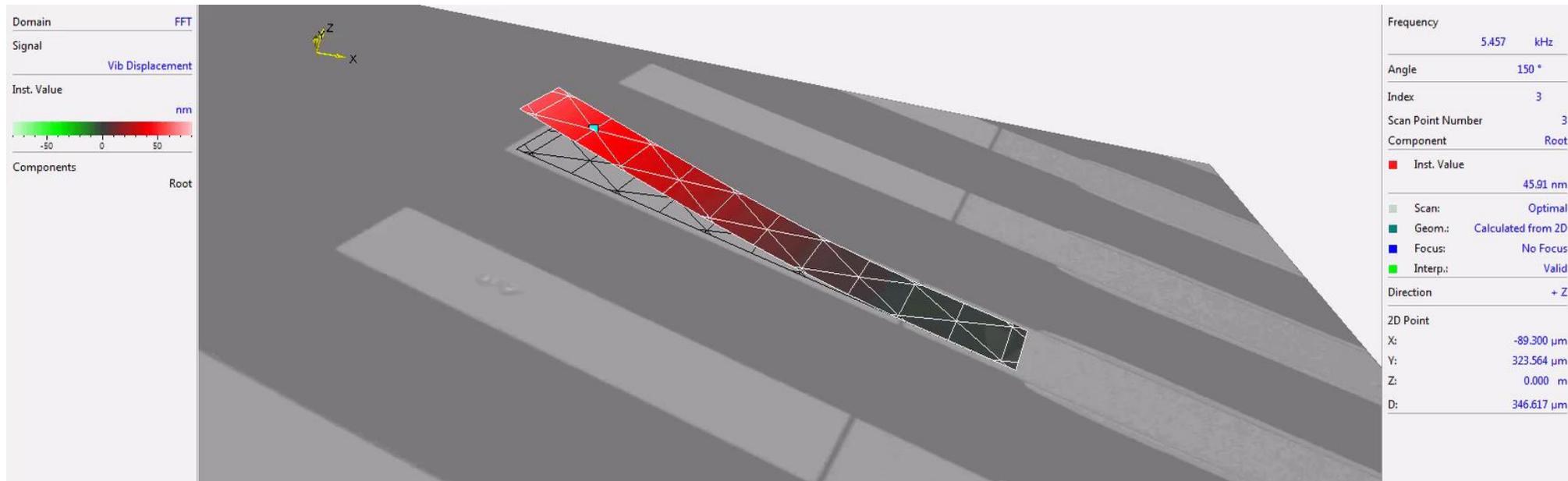




Instrumentação

Vibrômetro Laser Doppler

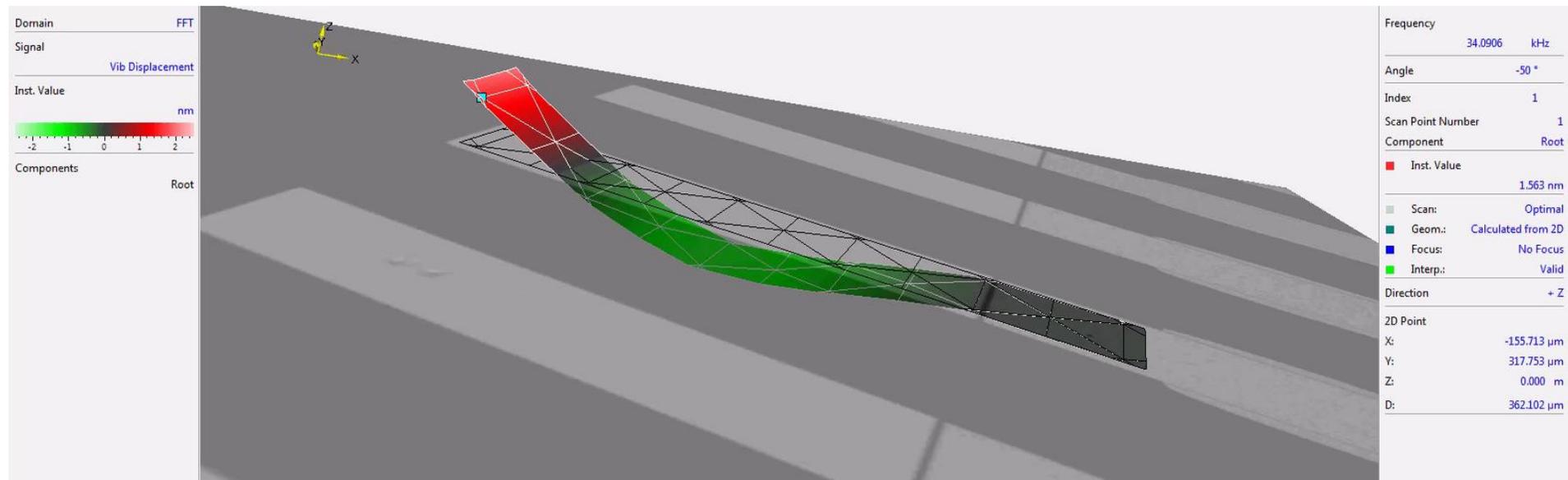
- Algumas medidas:



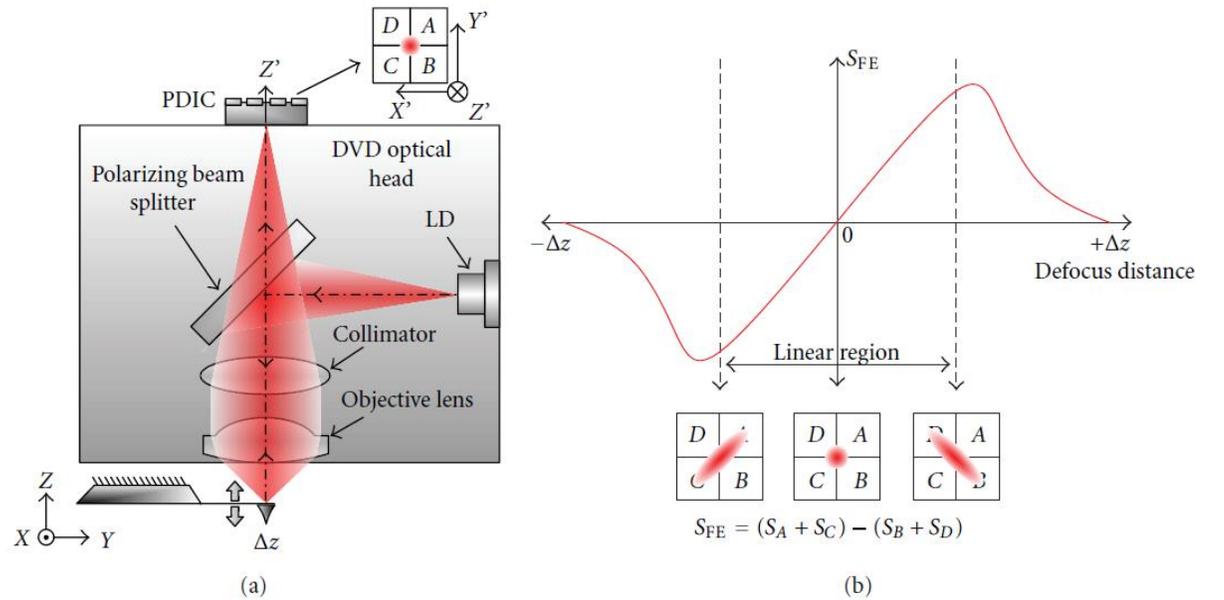
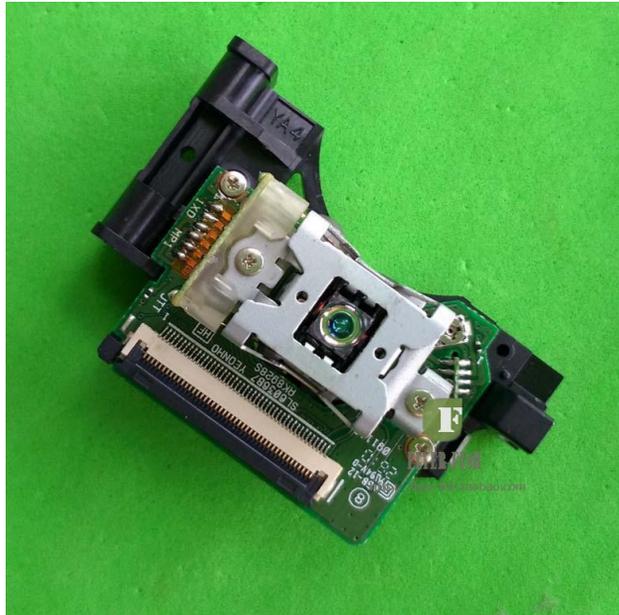
Instrumentação

Vibrômetro Laser Doppler –

- Algumas medidas:



Desenvolvimento de sistema para medida de dispositivo micromecânicos



Research Article

An Astigmatic Detection System for Polymeric Cantilever-Based Sensors

En-Te Hwu,¹ Hsien-Shun Liao,^{1,2} Filippo G. Bosco,³ Ching-Hsiu Chen,¹ Stephan Sylvest Keller,³ Anja Boisen,³ and Kuang-Yuh Huang²

¹ Institute of Physics, Academia Sinica, Nankang, Taipei 11529, Taiwan

² Department of Mechanical Engineering, National Taiwan University, Taipei 10617, Taiwan

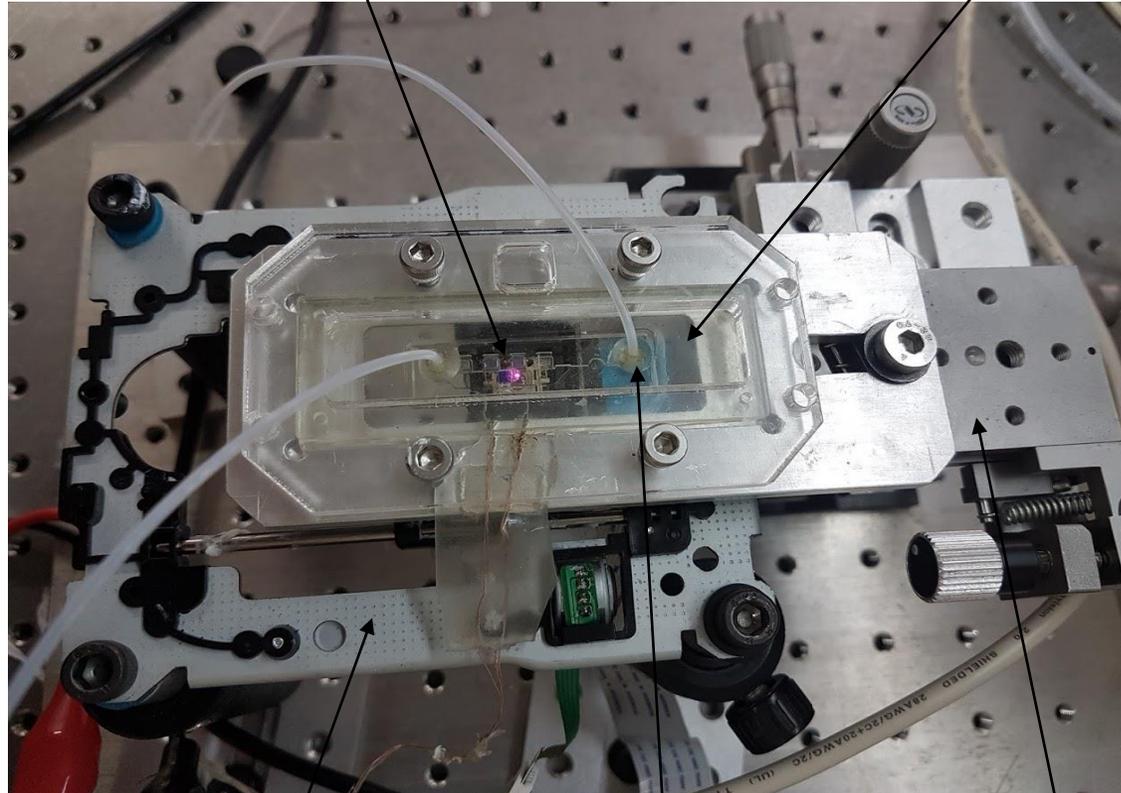
³ Department of Micro- and Nanotechnology, Technical University of Denmark, 2800 Lyngby, Denmark

Correspondence should be addressed to En-Te Hwu, whoand@phys.sinica.edu.tw

Sistema de medidas

Chip e sensor de temperatura

Célula de fluxo

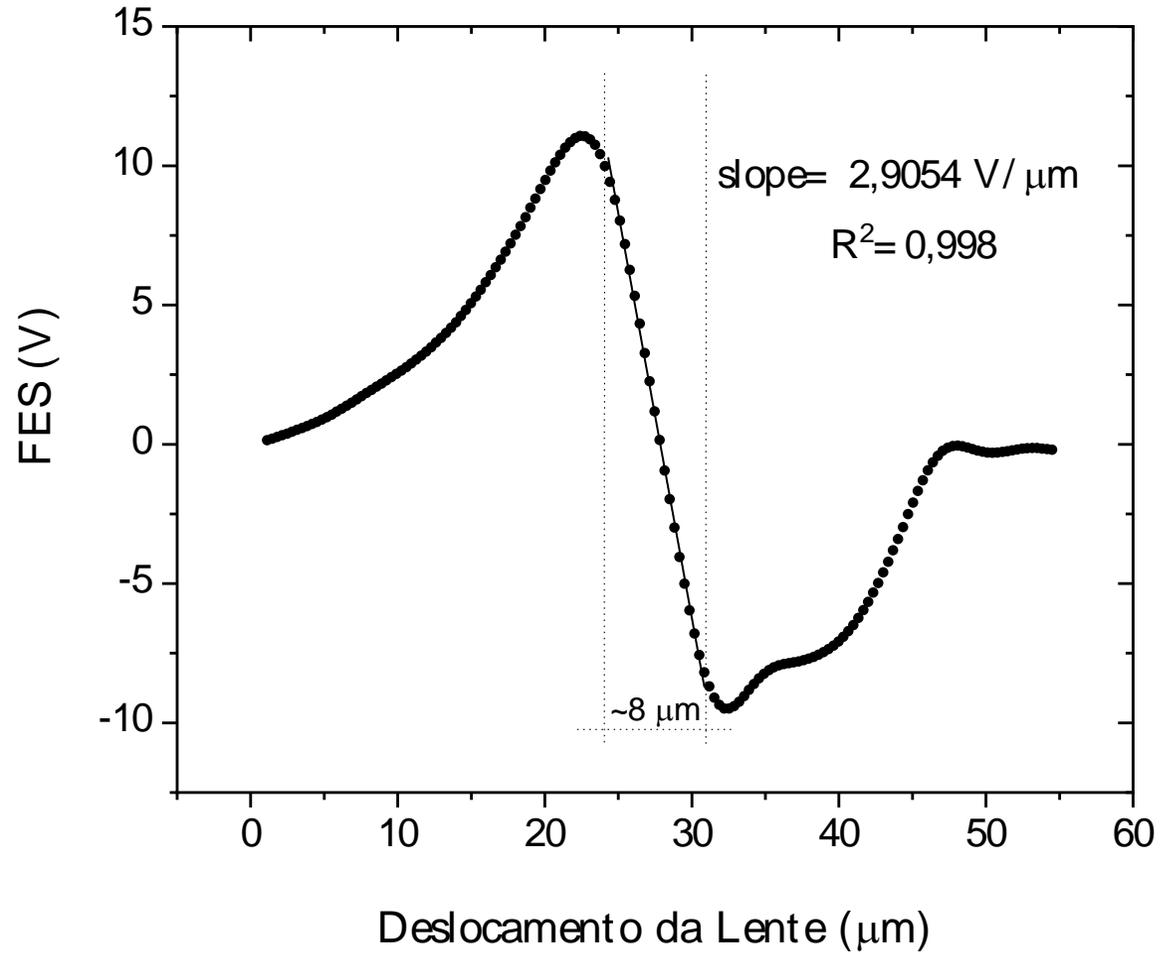
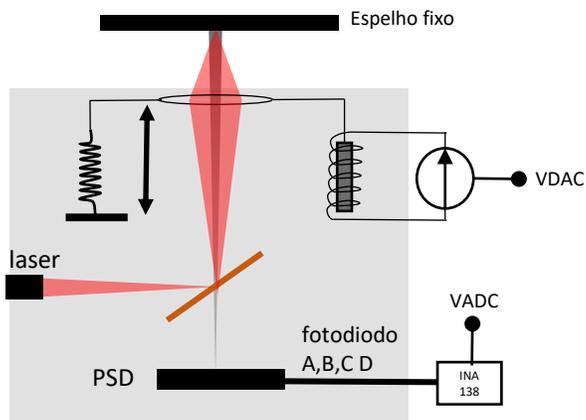


Pick-up

Entrada de gás

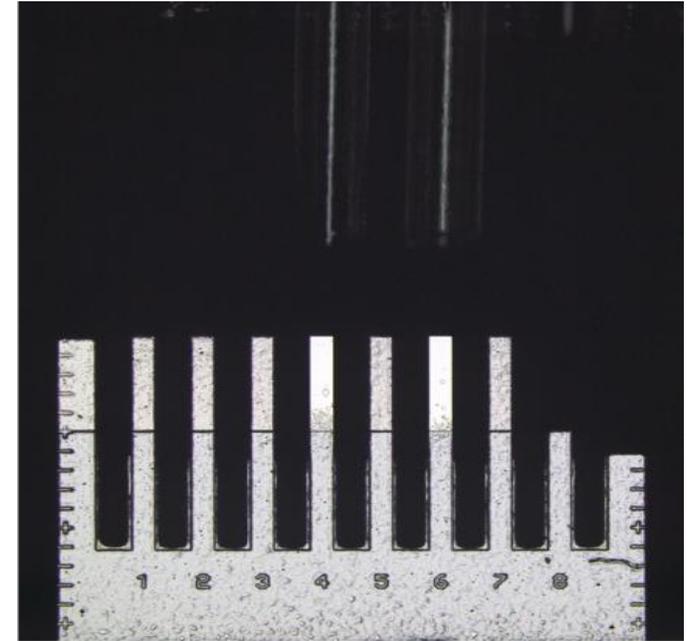
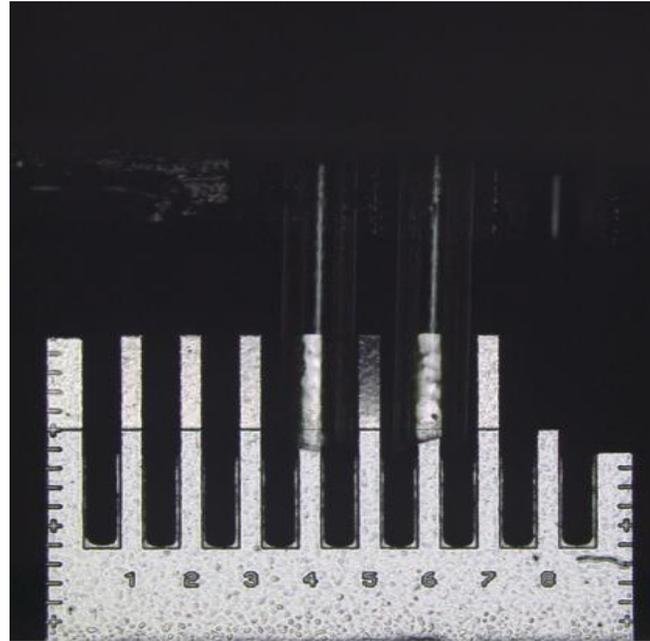
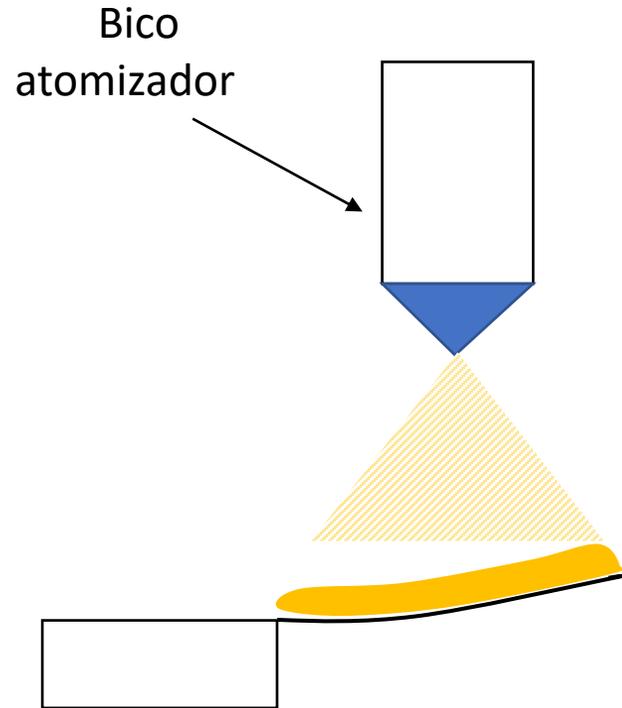
Estágio x, y, z e theta

Medida da curva FES

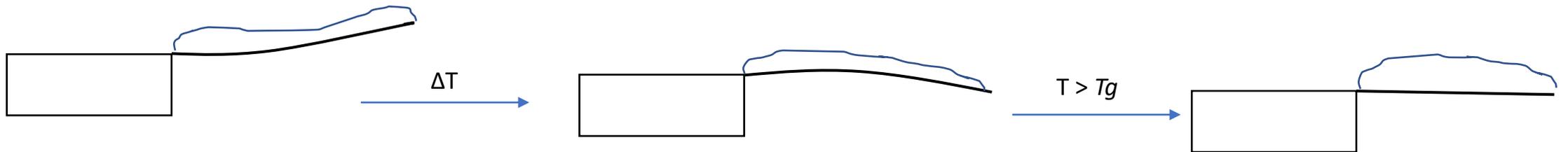
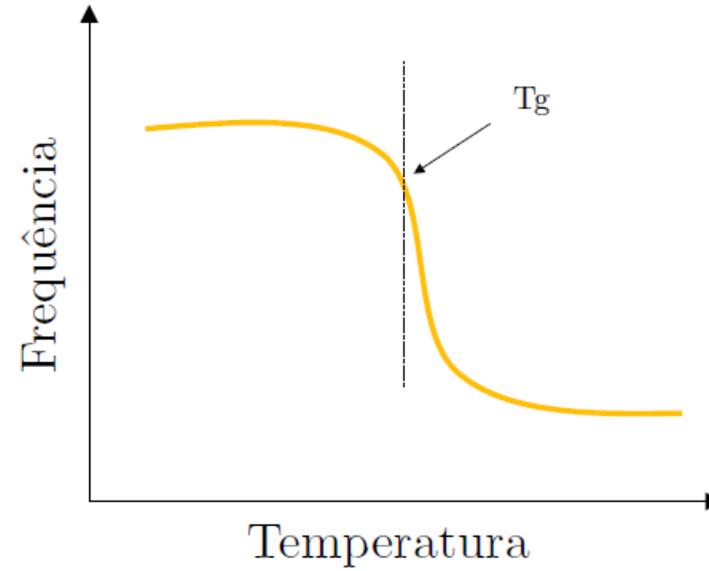
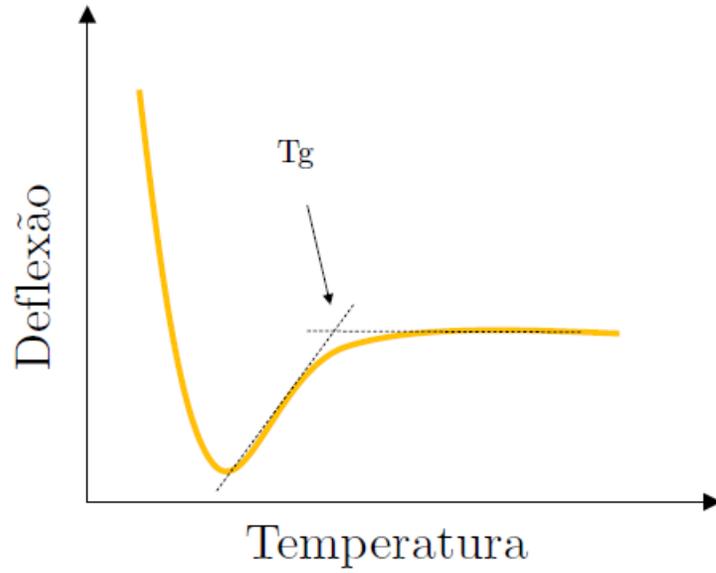




Deposição do PLGA sobre microcantilever

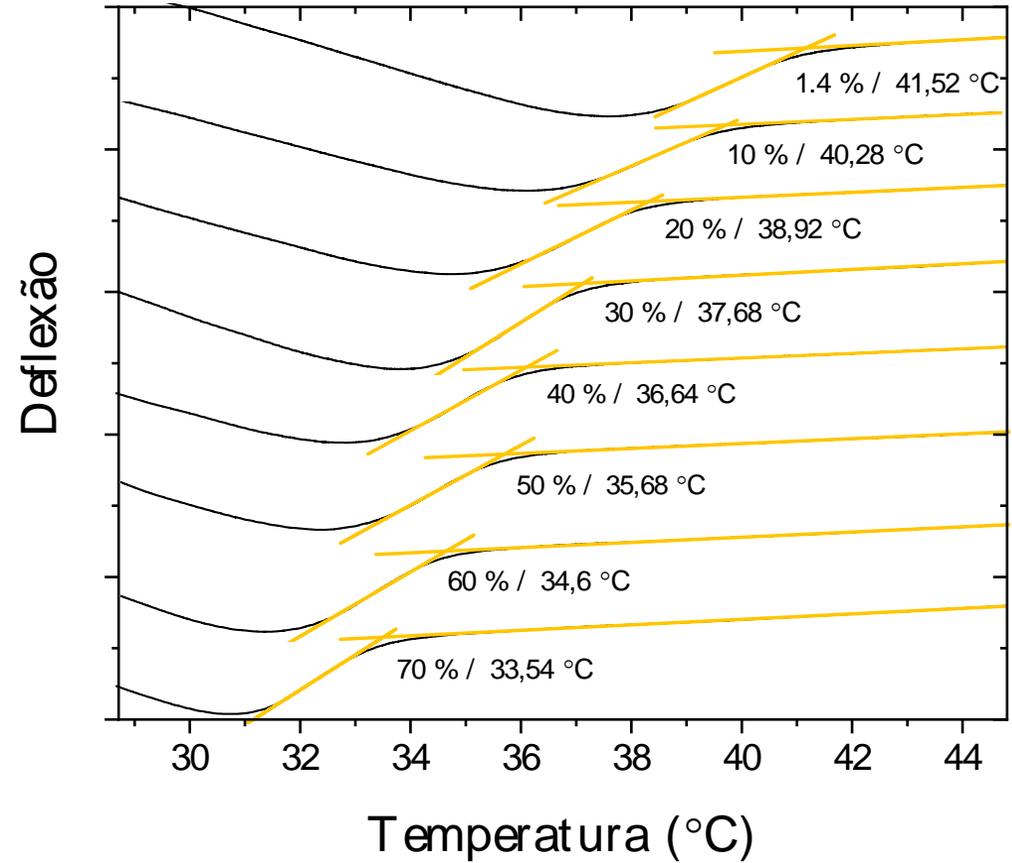
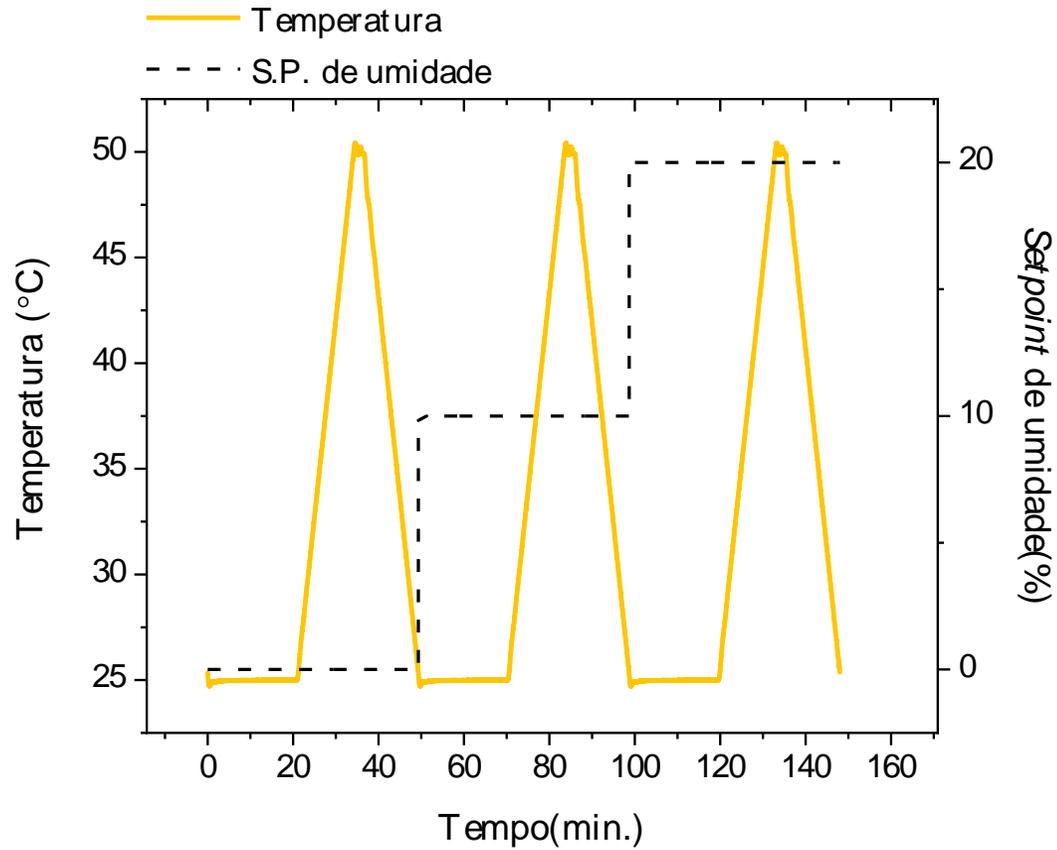


Caracterização térmica com microcantilever

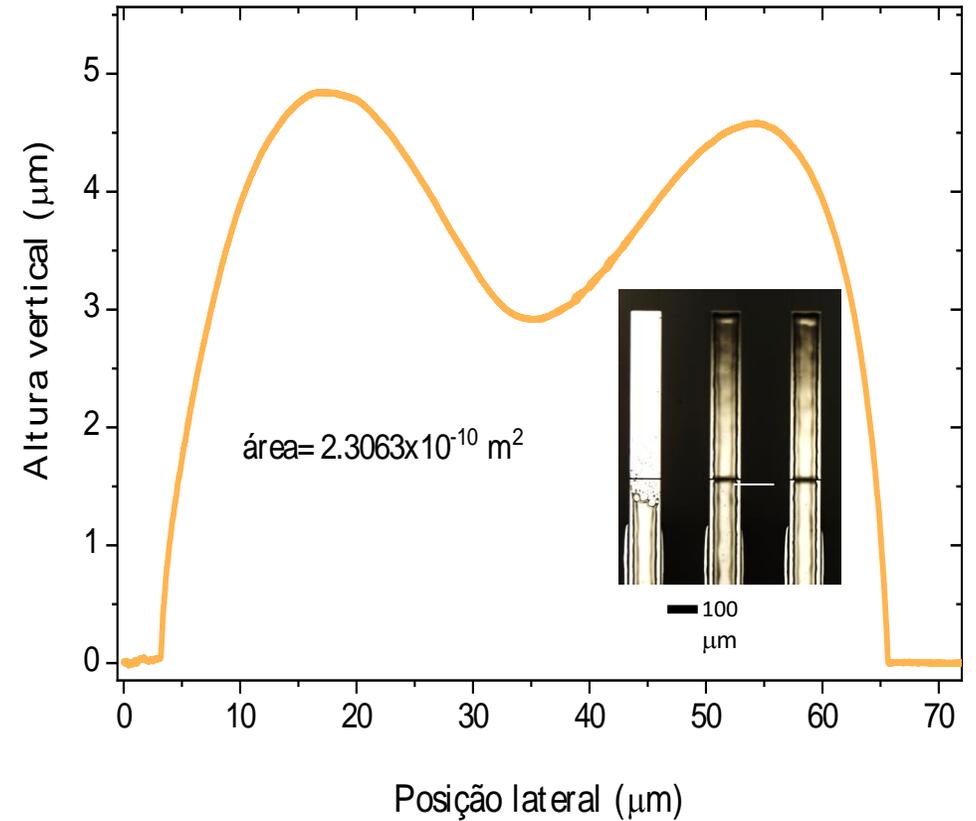
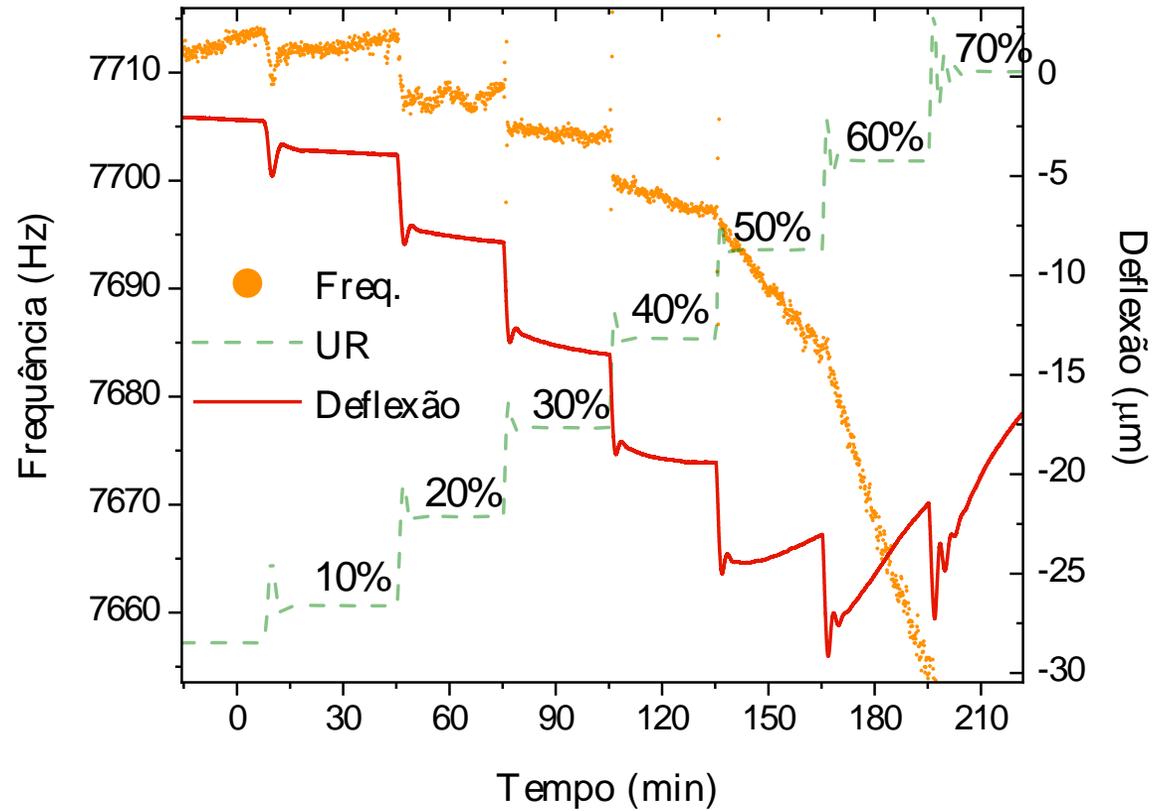




Tg versus umidade relativa

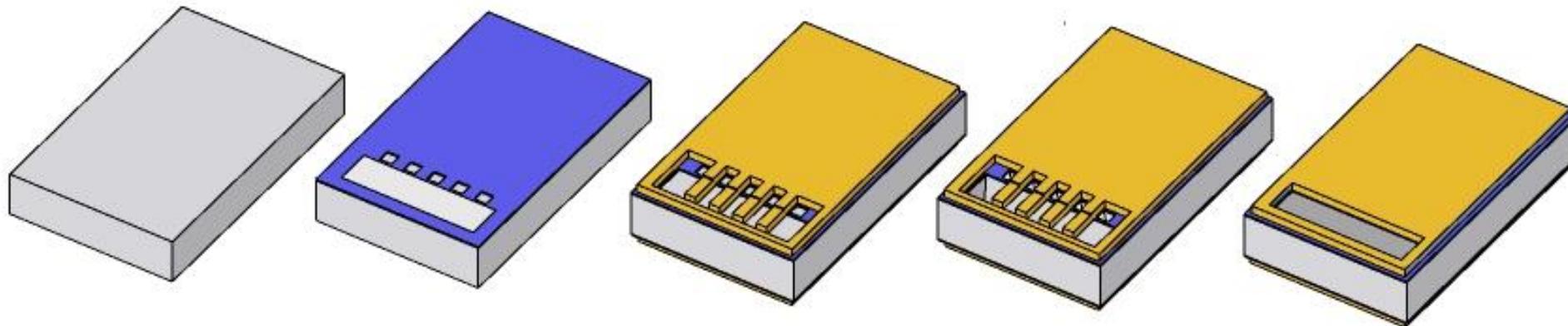


Medida da massa de água no polímero

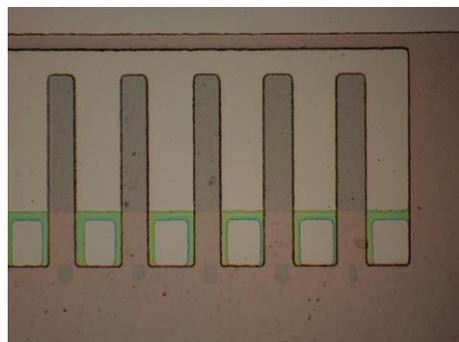




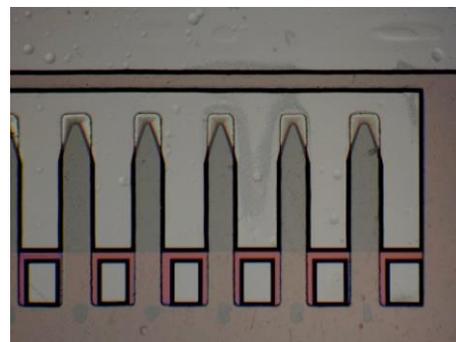
Fabricação de matrizes de cantileveres poliméricos



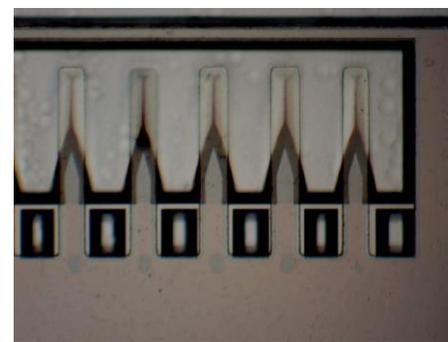
0 μm



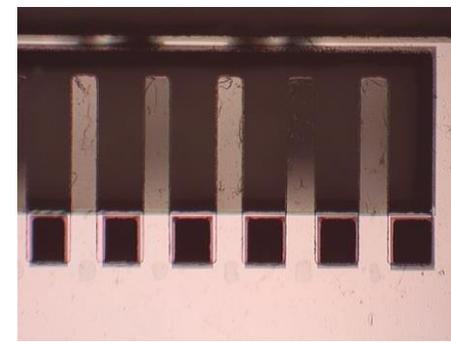
26 μm



76 μm

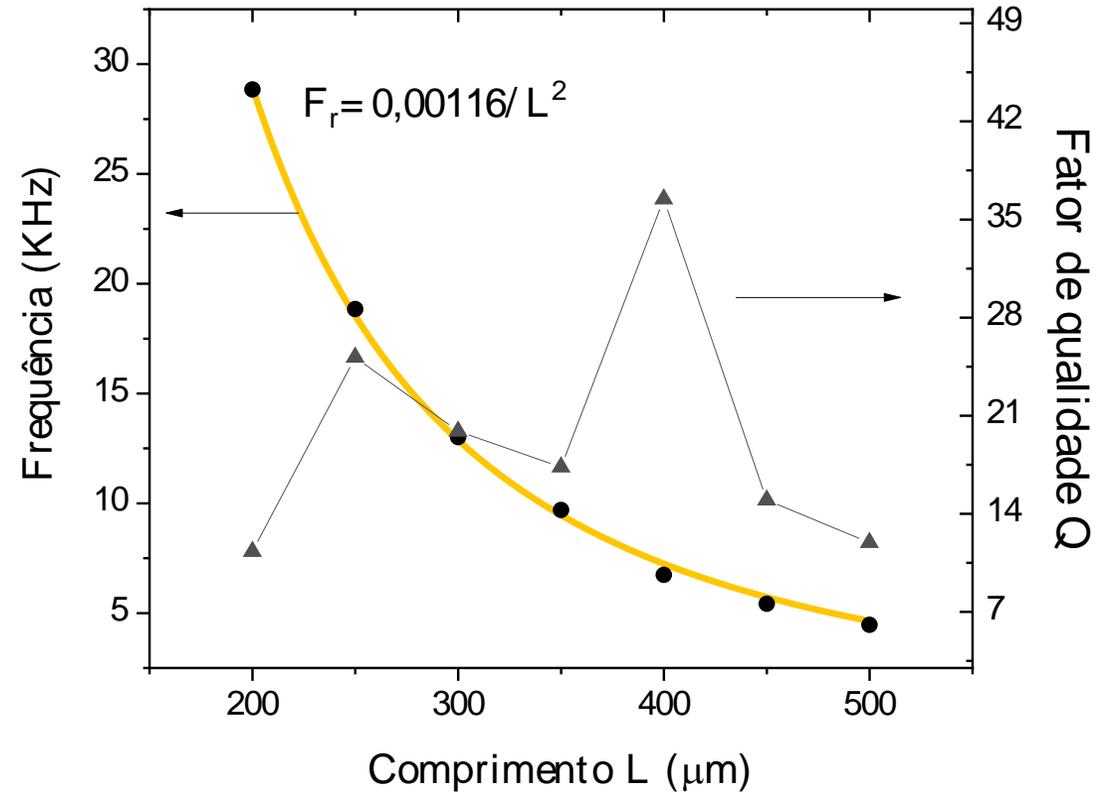
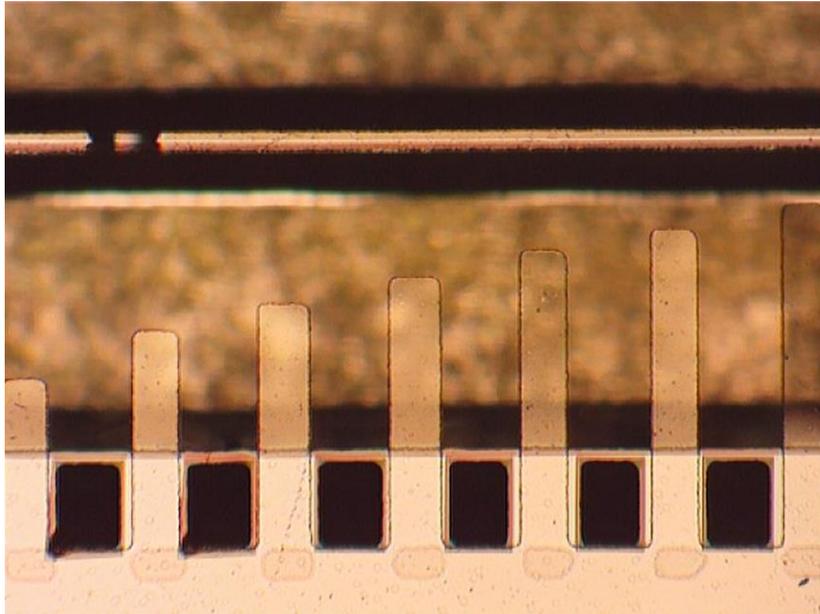


190 μm



100 μm

Caracterização dinâmica

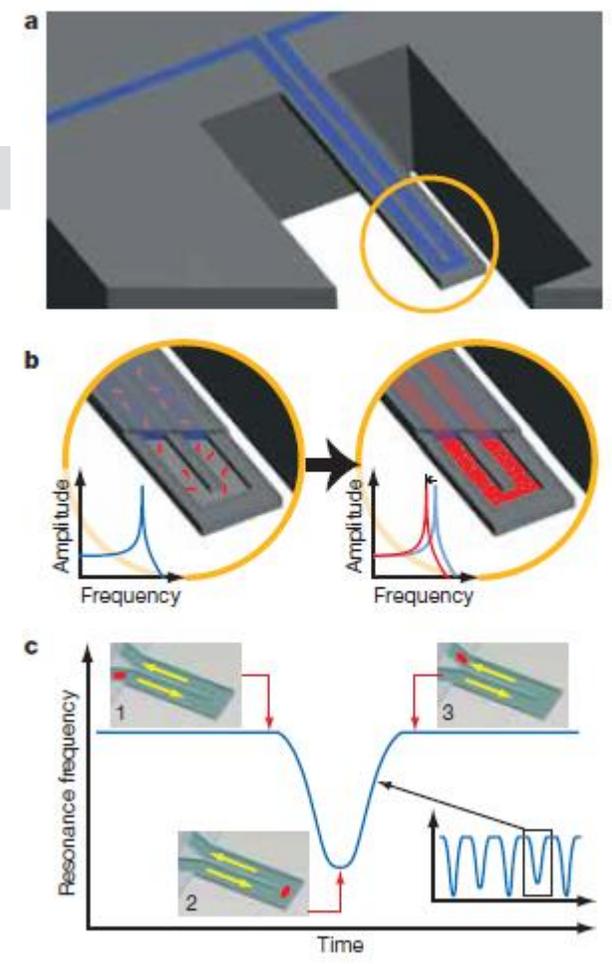


nature Vol 446 | 26 April 2007 | doi:10.1038/nature05741

LETTERS

Weighing of biomolecules, single cells and single nanoparticles in fluid

Thomas P. Burg^{1*}, Michel Godin^{1*}, Scott M. dsen¹, Wenjiang Shen³, Greg Carlson³, John S. Foster³, Ken Babcock^{3,4} & Scott R. Manalis^{1,2}





ARTICLE

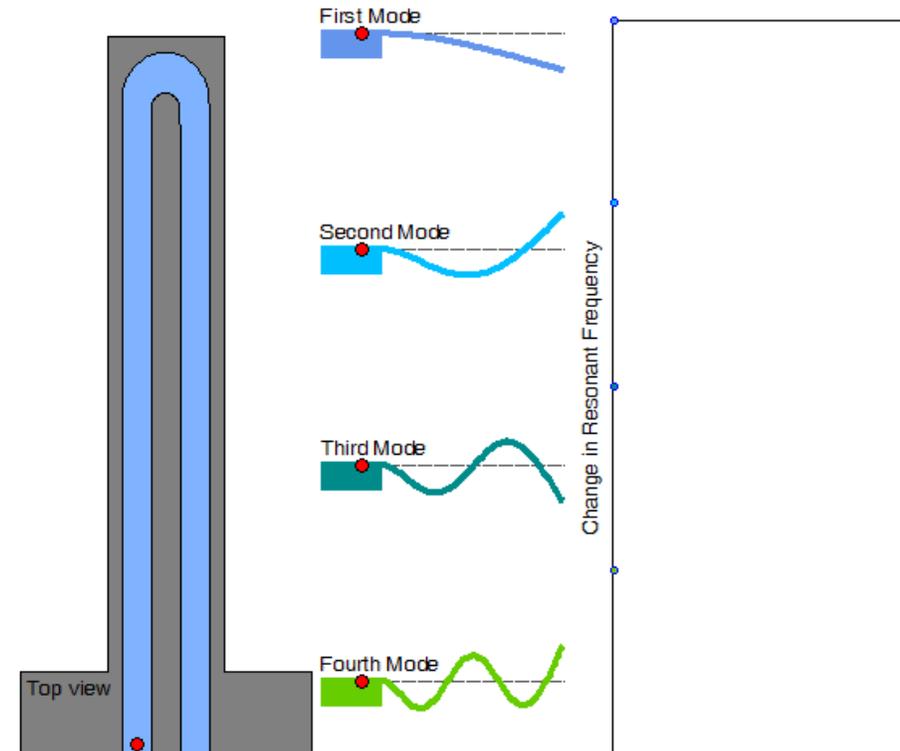
Received 25 Nov 2014 | Accepted 28 Mar 2015 | Published 12 May 2015

DOI: 10.1038/ncomms8070

OPEN

High-speed multiple-mode mass-sensing resolves dynamic nanoscale mass distributions

Selim Olcum^{1,*}, Nathan Cermak^{2,*}, Steven C. Wasserman³ & Scott R. Manalis^{1,2,3,4}



Sensors and Actuators B 233 (2016) 667–673

Contents lists available at ScienceDirect



Sensors and Actuators B: Chemical

journal homepage: www.elsevier.com/locate/snb



Nanomechanical IR spectroscopy for fast analysis of liquid-dispersed engineered nanomaterials

Alina J. Andersen^{*,1}, Shoko Yamada¹, E.K. Pramodkumar, Thomas L. Andresen, Anja Boisen, Silvan Schmid

Department of Micro- and Nanotechnology, Technical University of Denmark, DTU Nanotech, DK-2800 Kgs. Lyngby, Denmark

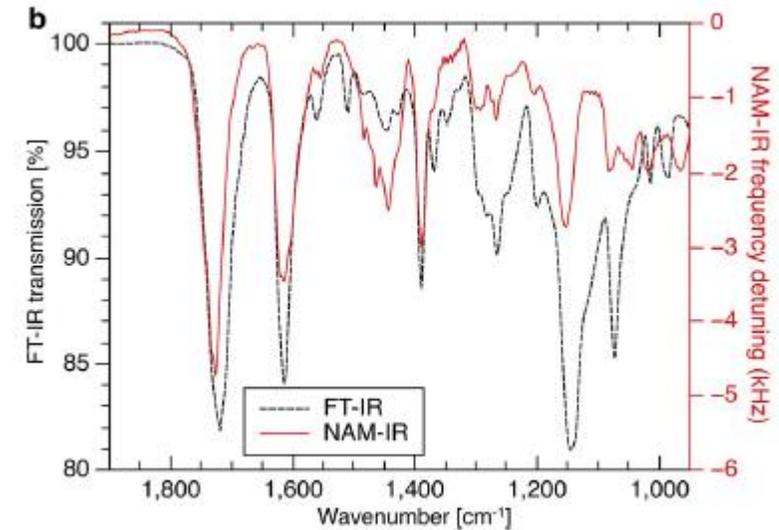
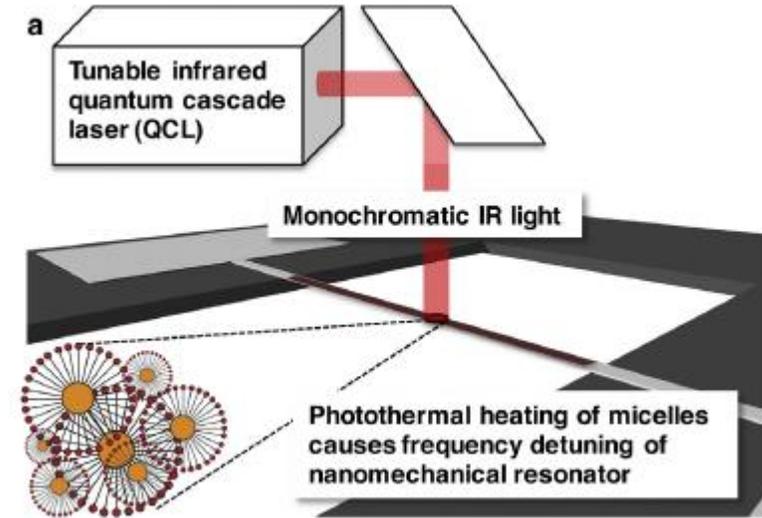


Fig. 7. (a) Schematic drawing of the NAM-IR method. The micelles collected on the



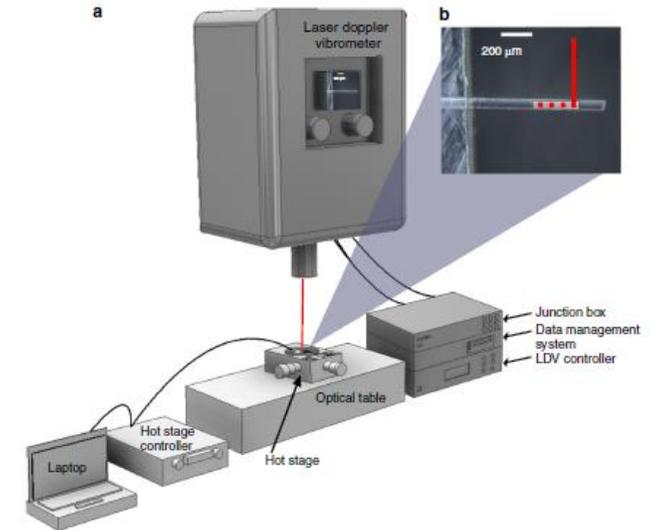
ARTICLE

Check for updates

<https://doi.org/10.1038/s41467-020-15028-y> OPEN

Single particles as resonators for thermomechanical analysis

Peter Ouma Okeyo^{1,2,3} , Peter Emil Larsen^{2,3}, Eric Ofosu Kissi ⁴, Fatemeh Ajalloueiian^{2,3}, Thomas Rades¹, Jukka Rantanen¹ & Anja Boisen ^{2,3}



A schematic and operation. **a** Schematic representation of the measurement setup for PMTA where the junction box, data management system, and LDV controller are used for operating and managing the data generated from the LDV. **b** Optical image of a single particle (TP MH) used as a cantilever with a laser spot on top (red) from the LDV as well as a measurement grid with red spots that are defined using the LDV software. The particle is mounted on a 5 mm x 5 mm aluminium block (left side of the image). A piezoelectric crystal was placed adjacent to the aluminium block during the measurements.



ARTICLE

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OPEN

Neutral particle mass spectrometry with nanomechanical systems

Eric Sage^{1,2}, Ariel Brenac^{3,4}, Thomas Alava^{1,2}, Robert Morel^{3,4}, Cécilia Dupré^{1,2}, Mehmet Selim Hanay^{5,†}, Michael L. Roukes⁵, Laurent Duraffourg^{1,2}, Christophe Masselon^{1,6,7} & Sébastien Hentz^{1,2}

established MS system. This lack of comparison probably stems from the fact that NEMS operate in a mass range where there is no accepted mass standard (i.e., the atomic or molecular calibrants used in MS^{23,24}). Furthermore, NEMS-MS has an

and readily condenses into large clusters. The cluster populations generated follow a log normal distribution law with mean mass of up to 4.5 MDa (diameter up to 9.5 nm). The TOF NEMS-MS mass spectra acquired for various populations

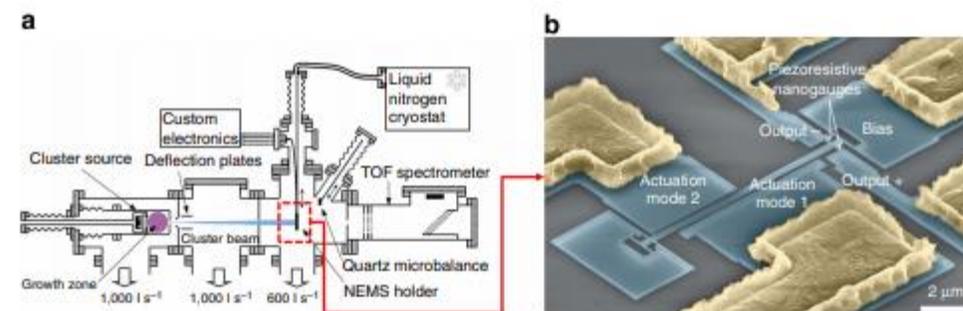


Figure 1 | Hybrid setup for TOF-MS and NEMS-MS of nanoparticles. (a) Diagram showing the full setup from left to right: the cluster source, intermediate chamber comprising deflection plates, the deposition chamber and an in-line TOF mass spectrometer. Both NEMS holder and QCM are retractable, making sequential NEMS-MS, TOF-MS and QCM measurements possible in identical operating conditions. (b) Coloured scanning electron microscope image of a typical doubly clamped in-plane resonator used in this study. The beams were designed to resonate around 25 MHz for mass



Obrigado pela atenção